



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 09/360,292
Filing Date July 22, 1999
Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc.
Group Art Unit 1746
Examiner Shamim Ahmed
Attorney's Docket No. MI22-1106
Title: Plasma Etching Process

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached Form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included herewith. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 10-27-2003

By: Jennifer J. Taylor
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Form PTO-1449

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MI22-1106SERIAL NO.
09/360,292LIST OF ART CITED BY APPLICANT
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APPLICANT: Sujit Sharan et al.

FILING DATE
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U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,051,503	04-2000	Bhardwaj et al.			
	AB	5,880,005	03-1999	Tsai et al.			
	AC						
	AD						
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FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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EXAMINER

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